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U. S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

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Application Number	10/616,735
Filing Date	July 10, 2003
Applicant(s)	Erik Nilsen et al.
Art Unit	Unknown
Examiner Name	Unknown
Attorney Docket Number	34003.77

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

SHEET 1 OF 1

U. S. PATENT DOCUMENTS

Examiner's Initials	Cite No.	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
JH	AA	6,131,277	10/17/2000	Cadenhead et al.
JH	AB	6,193,139	02/27/2001	Kivilahti
JH	AC	6,429,113	08/06/2002	Lewis et al.

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Examiner's Initials	Cite No.	Foreign Patent Document (Country Code - Number - Kind)	Publication Date MM-DD-YYYY	Patentee or Applicant of Cited Document	Translation YN

OTHER PRIOR ART

Examiner's Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article, title of the item, date, page(s), volume, issue number(s), publisher, city/country, where published
M	AD	Harsh et al., "Solder Self-Assembly for MEMS," Proceedings of the 1998 International Instrumentation Symposium (ISA'98), Reno, NV, pp. 256-261, May 3-7, 1998.
M	AE	Harsh et al., "Flip-Chip Assembly for Si-Based RF MEMS," Proceedings of the 1999 IEEE International Conference on Microelectromechanical Systems (MEMS '99), Orlando, FL, pp. 273-278, January 17-21, 1999.
M	AF	Gracias et al., "Forming Electrical Networks in Three Dimensions by Self-Assembly," Science, Volume 289, pp. 1170-1172, August 18, 2000.

Examiner Signature	<i>T. V.</i>	Date Considered	4/11/06
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Application Number	10/616735
Filing Date	07/10/2003
Applicant(s)	Nilsen et al.
Art Unit	2812
Examiner Name	To be Determined
Attorney Docket Number	34003.77

SHEET 1 OF 4

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Examiner's Initials	Cite No.	Document Number	Publication Date MM/YYYY	Name of Patentee or Applicant of Cited Document
IV	A1	3268774	08/1966	Ortner
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SHEET 2 OF 4

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Examiner's Initials	Cite No.	Document Number	Publication Date MM/YYYY	Name of Patentee or Applicant of Cited Document
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	A47	20010010348	08/2001	Bilanin et al.
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Examiner's Initials	Cite No.	Foreign Patent Document (Country Code - Number - Kind)	Publication Date MM/YYYY	Patentee or Applicant of Cited Document	Translation Y/N
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	B7	DE19746585	04/1999	Merck Patent GMBH	English Abstract and US Equivalent 6488315

NON-PATENT LITERATURE DOCUMENTS

Examiner's Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article, title of the item, date, page(s), volume-issue number(s), publisher, city/country where published
M	C1	Arai et al., "A New Pick Up & Release Method By Micromanipulation," IEEE, January 1997.
M	C2	Capanu et al., "Design, Fabrication, and Testing of a Bistable Electromagnetically Actuated Microvalve", Journal of Microelectromechanical Systems, Vol. 9, No. 2, June 2000, pp. 181-188.

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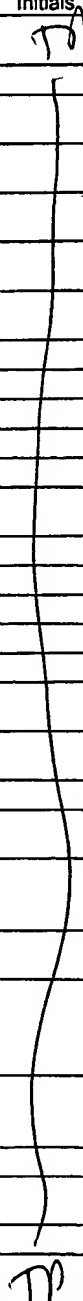
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
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	C16	International Preliminary Examination Report in PCT/US01/015011 dated September 13, 2002.
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